

[10191/3980]

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s) : Franz LAERMER
Serial No. : 10/519,724
Filed : December 28, 2004
For : DEVICE AND METHOD FOR THE PRODUCTION OF
CHLORINE TRIFLUORIDE AND SYSTEM FOR
ETCHING SEMICONDUCTOR SUBSTRATES USING
THIS DEVICE
Examiner : Rakesh Dhingra
Art Unit : 1716
Confirmation No. : 5180

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

I hereby certify that this correspondence is electronically
transmitted to the USPTO via the Office of electronic filing
system on: Date: September 3, 2010

Signature: /Kevin Kambo/
Kevin Kambo

REPLY UNDER 37 C.F.R. § 1.116

S I R:

In response to the Office Action of June 3, 2010, for which the three-month period of response expires on September 3, 2010, kindly amend the above-captioned application without prejudice as follows:

Amendments to the claims are not presented in this paper.
Nevertheless, a **Listing of Claims** begins on page 2 of this paper for the convenience of the Office.

Remarks begin on page 6 of this paper.

While no fees are believed to be due, the Commissioner is authorized, as appropriate and/or necessary, to charge any fees or credit any overpayment to **Deposit Account No. 11-0600.**